# Korean Filing Date: June 1, 2000

## TJK/180/L.W.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of Hong-Sik BYUN et al.	)	PLASMA PROCESSING APPARATUS
Korean Appln. No. 2000-30050	)	
Korean Filing Date: June 1, 2000	)	

# PRELIMINARY AMENDMENT

Assistant Commissioner for Patents Washington, D.C. 20231

Dear Sir:

C)

Please amend the subject application as follows:

# -- CROSS REFERENCE TO RELATED APPLICATION

This application claims the priority of Korean patent application Serial No. 2000-30050

filed on June 1, 2000.-

Respectfully submitted,

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I hereby certify that this paper or the is being resurrance with United States Postal Service Express Mail Print State Addressee" on the date indicated above and is addressed to Assistant Commissioner For Parents, washington, Oct. 2022